

# Netherlands-Korea Semiconductor Tech Seminar

## 한-네덜란드 반도체기술협력 세미나



Thursday, 12 February, 2026 / 2026년 2월 12일 목요일  
COEX Conference Room #318 / 코엑스 컨퍼런스룸 318호

Register Here



<https://link24.kr/ChgDoOz>

Co-organizers: Korea Semiconductor Industry Association,  
SoBuJang Technology Collaboration Forum, Embassy of the Kingdom of the Netherlands

### Netherlands Tech Pitching Lunch (Lunch & Launch)

11:00-11:30	Registration
11:30-11:35	Opening & Greeting
11:35-12:40	Pitching by Dutch entities (3min / company) : <ul style="list-style-type: none"> <li>- High Tech NL</li> <li>- Schunk Xycarb Technology</li> <li>- Bronkhorst</li> <li>- Levitech B.V.</li> <li>- Mecal-HTS</li> <li>- Prodrive Technologies</li> <li>- Sioux Technologies</li> <li>- Tempres Systems B.V.</li> <li>- Minds.ai</li> <li>- TNO</li> <li>- TU Eindhoven</li> <li>- GI-Ventures</li> <li>- Investment International B.V.</li> <li>- Province of Noord Brabant</li> </ul>
12:40-13:00	Networking
13:00-14:00	Break & Registration

### Netherlands-Korea Semiconductor Tech Seminar

Session 1: Semiconductor Ecosystem in the Netherlands and Korea		
14:00-14:05	Opening & Greeting	Embassy
14:05-14:10	Congratulatory remark	Aukje de Vries, Minister for Foreign Trade and Development
14:10-14:20	Dutch Semiconductor Ecosystem	Naomie Verstraeten, Brainport Development
14:20-14:30	Korea Semiconductor Industry Introduction	Jaemin Jun, Korea Semiconductor Industry Association
14:30-14:35	Q&A	
Session 2: EUV technologies and metrology		
14:35-14:45	ASML: EUV development strategy and plan	Roderik van Es, ASML
14:45-14:55	TNO: EUV and metrology technologies	Helen Kardan, TNO
14:55-15:05	Developing EUV Mask Metrology for High-Volume Manufacturing	Byung Gook Kim, ESOL
15:05-15:15	Semiconductor / EUV Lithography and related MI technology, Synchrotron science	Sangsul Lee, Postech
15:15-15:20	Q&A	
15:20-15:30	Coffee Break	
Session 3: Material & Equipment Development		
15:30-15:40	Opportunities for cooperation in the SoBuJang field of semiconductors	Hak Kyung Sung, SoBuJang Forum
15:40-15:50	Introduction of LGE PRI (semiconductor Equipment)	Joo Won Lee, LG Electronics
15:50-16:00	Contract Engineering in the Netherlands	Sven Pekelder, Settels Savenije
16:00-16:10	Horizontal integration partner for semiconductor equipment development	Dongha Kim, Prodrive Technologies
16:10-16:20	Predicting Device-Relevant Properties in ALD and ALE via Multiscale Surface-to-Device Simulation	Fedor Goumans, Software for Chemistry & Materials
16:20-16:25	Q&A	
Session 4: New Device		
16:25-16:35	Status for DBH SiC/GaN Technology development	Sang Gi Lee, DB HiTek
16:35-16:45	Photonic Integrated Circuit	Dongjae Shin, IMEC
16:45-16:50	Q&A	
16:50-17:00	Closing & Networking	

\* Lunch is served during the Pitching and Networking.

\* Language: English / Korean (Simultaneous interpretation provided only during Session 1, 2, 3 and 4)

\* Inquiry : [SEO-EA@minbuza.nl](mailto:SEO-EA@minbuza.nl)

\* The schedule and program details may be subject to change depending on operational circumstances.